

IN THE CLAIMS:

Please **cancel** claims 21-32 without prejudice.

1. (Previously presented) An in-line system for manufacturing liquid crystal displays, comprising:

a sealant-applying unit depositing sealant on one of two substrates, either one of the two substrates having at least one liquid crystal cell;

a sealant heat-treating unit forming a reaction-prevention layer on a surface of the sealant to prevent a reaction between the sealant and a liquid crystal material;

a liquid crystal depositing unit depositing the liquid crystal material on the substrate where the sealant is deposited;

a substrate-attaching unit receiving the two substrates from the sealant-applying unit or the liquid crystal depositing unit and conjoining the substrates in a vacuum state; and

an in-line convey unit conveying the substrates in the in-line system.

2. (Previously presented) The in-line system of claim 1, further comprising: a first loading unit loading one of the two substrates;

a second loading unit loading the other one of the two substrates; and

a substrate-combination unit providing the two substrates to the substrate-attaching unit.

3. (Cancelled)

4. (Previously presented) The in-line system of claim 2, wherein the first loading unit, the spacer-dispersing unit, the sealant-applying unit, the liquid crystal depositing unit, the substrate-combination unit, and the substrate-attaching unit are arranged in series.

5. (Previously presented) The in-line system of claim 4, wherein the second loading unit is connected to the substrate-combination.

6. (Previously presented) The in-line system of claim 2, wherein the first loading unit, the sealant-applying unit, the liquid crystal depositing unit, the substrate-combination unit, and the substrate attaching unit are arranged in series.

7. (Previously presented) The in-line system of claim 6, wherein the second loading unit, the spacer-dispersing unit and the substrate-combination unit are arranged in series.

8. (Previously presented) The in-line system of claim 1, wherein the substrate-attaching unit includes two or more vacuum chambers.

9. (Previously presented) The in-line system of claim 8, wherein the vacuum chambers are arranged in series.

10. (Previously presented) The in-line system of claim 8, wherein the vacuum chambers are arranged in parallel.

11. (Previously presented) The in-line system of claim 1, wherein the substrate-attaching unit comprises:

a first compression plate and a second compression plate supporting the two substrates and applying a predetermined force toward each other; and

an exposure unit hardening the sealant.

12. (Previously presented) The in-line system of claim 1, wherein the substrate-attaching unit comprises:

a first compression plate and a second compression plate for supporting the two substrates and applying a predetermined force toward each other, the first compression plate and the second compression plate having at least one vacuum hole for exhausting air from between the compression plates;

a support tube provided between the first compression plate and the second compression plate for sealing a space therebetween, the support tube having an inner space for exhausting air to adjust an interval between the first compression plate and the second compensation plate; and

an exposure unit hardening the sealant.

13. (Previously presented) The in-line system of claim 12, wherein the substrate-attaching unit has a plurality of the vacuum holes at predetermined locations for exhausting in a predetermined sequence.

14. (Previously presented) The in-line system of claim 13, wherein the vacuum holes are formed at corners or a center portion of each side of the first compression plate and the second compression plate.

15. (Previously presented) The in-line system of claim 13, wherein the vacuum holes are slits having a predetermined length.

16. (Previously presented) The in-line system of claim 1, wherein the liquid crystal depositing unit comprises a syringe-type liquid crystal depositer for depositing the liquid crystal material at specific predetermined locations in the liquid crystal cell.

17. (Previously presented) The in-line system of claim 1, wherein the liquid crystal depositing unit comprises is a spray type liquid crystal depositer for depositing the liquid crystal material over an entire surface of the liquid crystal cell.

18. (Previously presented) The in-line system of claim 1, wherein the sealant-applying unit deposits the sealant in a closed loop without a liquid crystal injection hole.

19. (Previously presented) The in-line system of claim 1, wherein the sealant is hardened by infrared rays.

20. (Previously presented) The in-line system of claim 1, wherein the sealant includes one or more buffer regions to allow flow of excess liquid crystal material.

21-55. (Cancelled)

56. (Previously presented) The in-line system of claim 1, further comprising a spacer-dispersing unit dispersing spacers on either one of two substrates.